



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Manoocher Birang et al. Art Unit : Unknown
 Serial No. : 09/399,310 Examiner : Unknown
 Filed : September 20, 1999
 Title : APPARATUS AND METHOD FOR IN-SITU ENDPOINT DETECTION FOR
 CHEMICAL MECHANICAL POLISHING OPERATIONS

Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

I. References

Copies of the references listed on the attached form PTO-1449 are enclosed.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits.

II. Other Information

Applicant also submits the following information:

A sample of a JR111 mounting pad, discussed as a possible pad material in U.S. Patent No. 5,489,233 to Cook et al., was tested and was found to transmit light in at least the wavelength range of 400-800 nm (the range of wavelengths emitted by the tungsten lamp used in the test). Similarly, a sample of Dow Isoplast 302EZ resin, discussed as a possible pad material in U.S. Patent No. 5,489,233 to Cook et al., was tested and was shown to transmit light in at least the wavelength range of 400-800 nm (the range of wavelengths emitted by the tungsten lamp used in the test).

Inventors Allan Gleason and Manoocher Birang received samples of a polishing pad material designated EX2000 from Rodel in the summer of 1994. The EX2000 polishing pad

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 18, 2003

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Applicant : Manoocher Birang et al.
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Attorney's Docket No.: 05542-146004 / 784-C3 - USA
F04/PDD/CMP/RKK

included a translucent top layer having grooves formed in its upper surface, and an opaque gray foam sublayer. In the samples they received in the summer of 1994, the opaque gray foam sublayer covered the entire bottom surface of the translucent top layer.


Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 9/18/03

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|  | Substitute Form PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | Attorney's Docket No. 05542-146004 | Application No. 09/399,310 |
| | Information Disclosure Statement by Applicant (Use several sheets if necessary) | | Applicant Manoocher Birang et al. | |
| | | | Filing Date September 20, 1999 | Group Art Unit Unknown |

U.S. Patent Documents

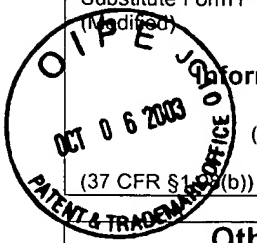
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| Examiner Signature | Date Considered |
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| Substitute Form PTO-1449 (Modified) | U.S. Department of Commerce Patent and Trademark Office | Attorney's Docket No. 05542-146004 | Application No. 09/399,310 |
| Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR § 1.97(b)) | | Applicant Manoocher Birang et al. | |
| | | Filing Date September 20, 1999 | Group Art Unit Unknown |


Other Documents (include Author, Title, Date, and Place of Publication)

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| Examiner Signature | Date Considered |
| EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | |